

Hungarian Academy of Sciences, Budapest



Founded in 1825



37 research institutions, supervised by HAS



**Research Institute for Technical Physics and
Materials Science**
Budapest, Hungary





Mission of the institute

Interdisciplinary research performed on complex functional materials and structures, studies of physical, chemical principles, development of characterization techniques, implementation into integrated micro- and nanosystems.

Dissemination of the results in international programs, involvement in education and in industrial R&D, with special attention to the needs of SME-s



Personnel

- **Total staff:** **150**

- **Scientific qualification:**
 - Member of HAS (1)
 - DSc 14 (+5)

 - PhD/CSc 46

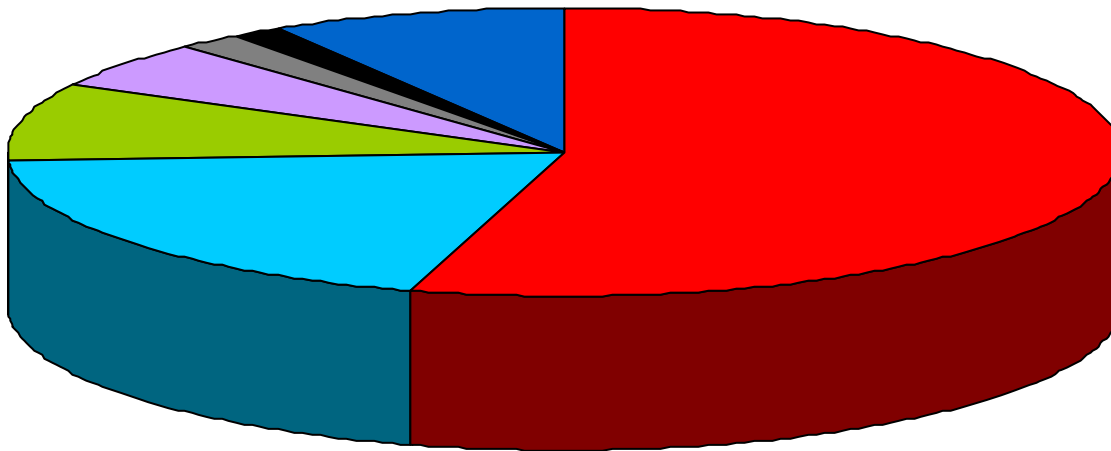
- **Research staff:** **100**
 - Emeritus Professor Instituti (6)
 - Sci. councillor 14
 - Senior researcher 34
 - Sci. researcher 38
 - Junior researcher 14+5
 - Graduate student 13

- **Technical, administrative staff:** **50**



Financing

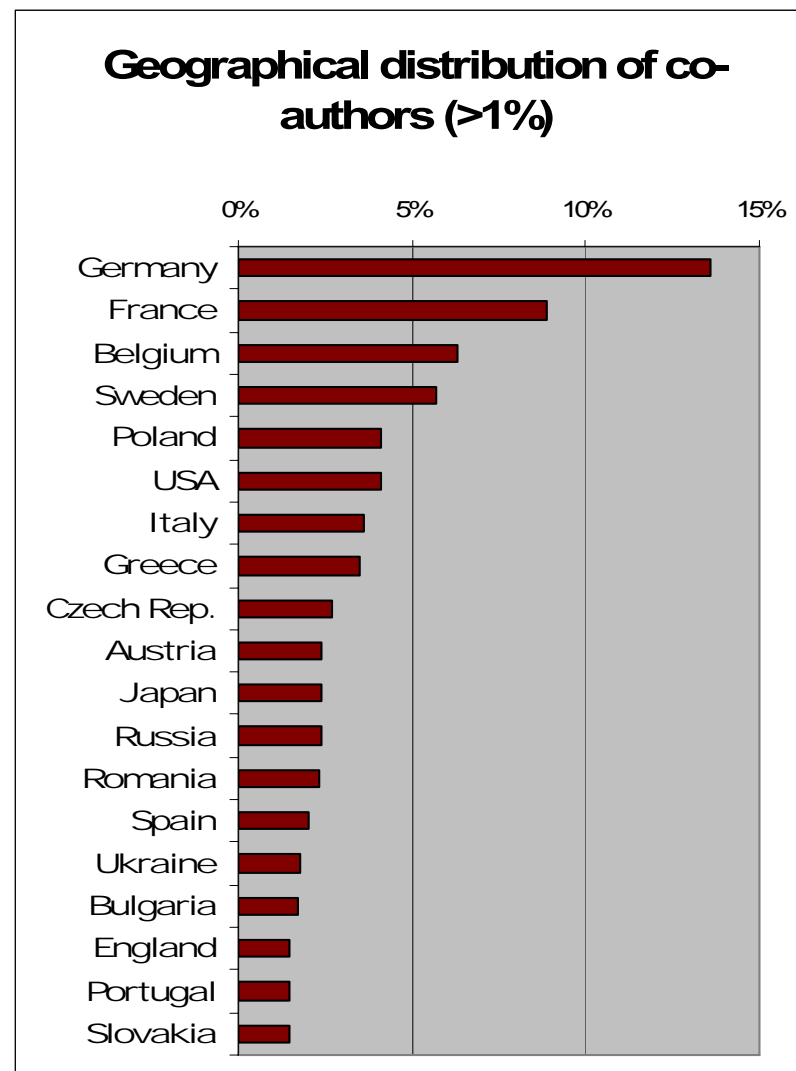
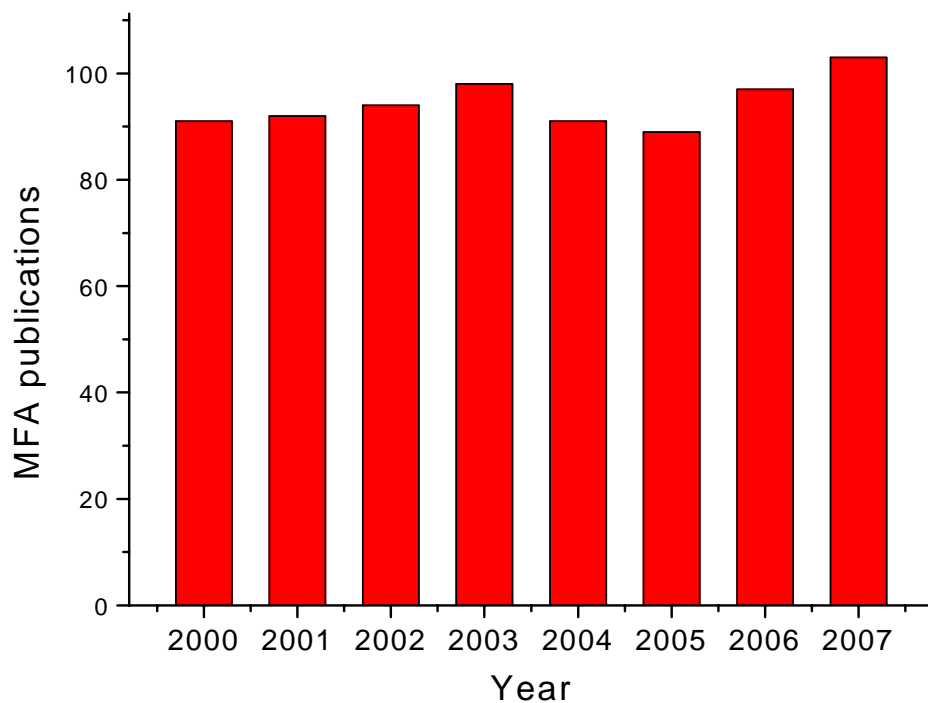
Total budget: cca. € 5.3 M



■ Central subsidy (MTA)	54,6%
■ Domestic project funding	19,6%
■ EU & NATO project funding	8,5%
■ Industrial RD contracts	5,5%
■ Profit-oriented activities	1,8%
■ R&D equipment subsidy	1,5%
■ Miscellenous categories	8,5%



ISI Web of Knowledge (2000-2007)



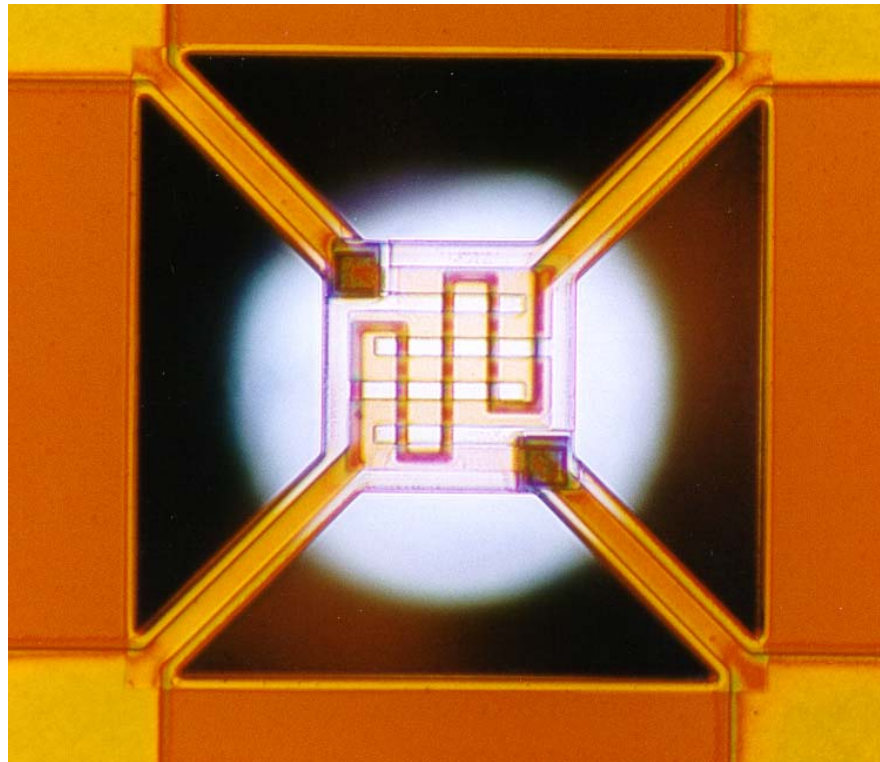


Points of excellence

- Clean lab (Class 10-10000) and Mask facility
- Electron Microscopy, Auger and Scanning Probe Lab
- Thin film, Surface Physics and Structures
- Ion Implantation and Ion Beam Analysis
- Optical Characterization, Ellipsometry
- Semiconductor Lasers and different LPE Techniques
- Sensorics; semiconductor (pressure, gas, microwave); magnetic (cracks in steel); optical waveguides (biosensor)
- Computing applications; medical (biopotentials, automatic cell identification, telemedicine)
- Porous silicon preparation and studies, SiC studies
- Carbon nanotubes, preparation and studies
- Computational physics
- Ceramics, high pressure, high temperature press; refractory metals

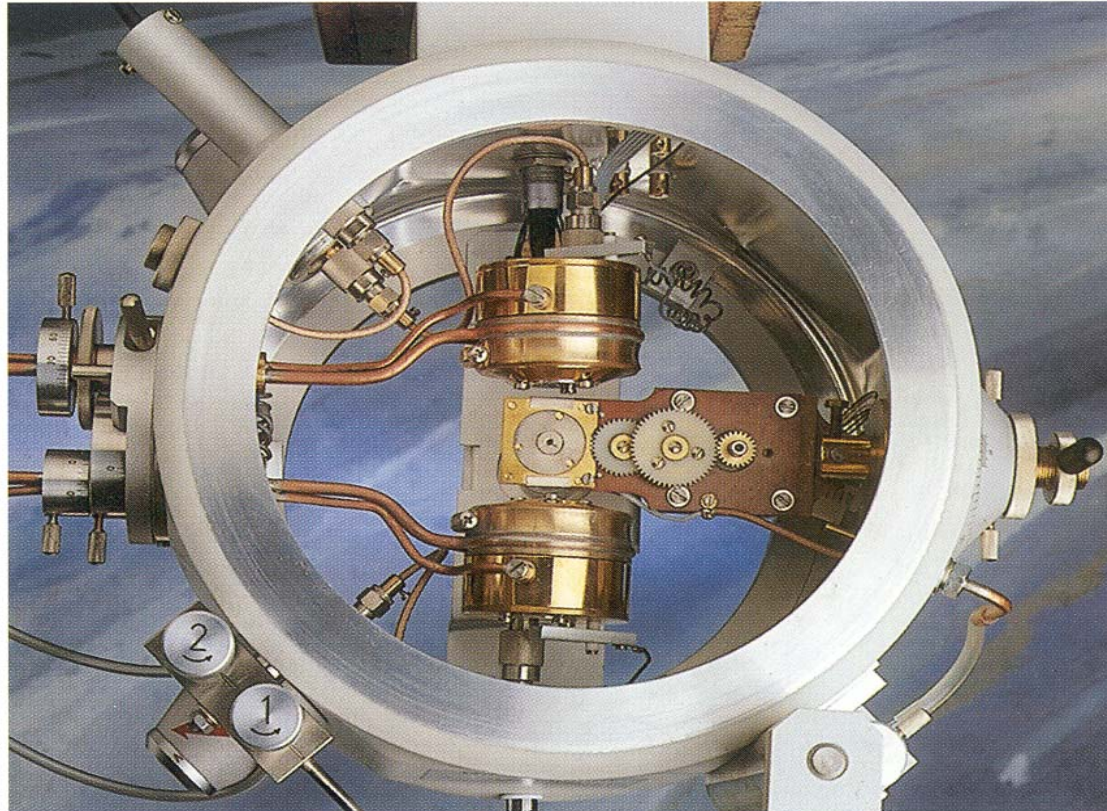
"Micro hotplate" for Taguchi and pellistor-type gas sensors on a MEMS SAFEGAS project

Gas sensing or catalytic material on the floating, heated $70 \times 70 \mu\text{m}^2$ Si/SiN membrane with heater + Pt thermometer

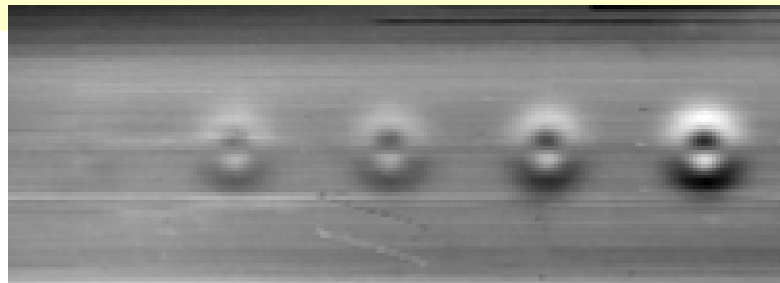
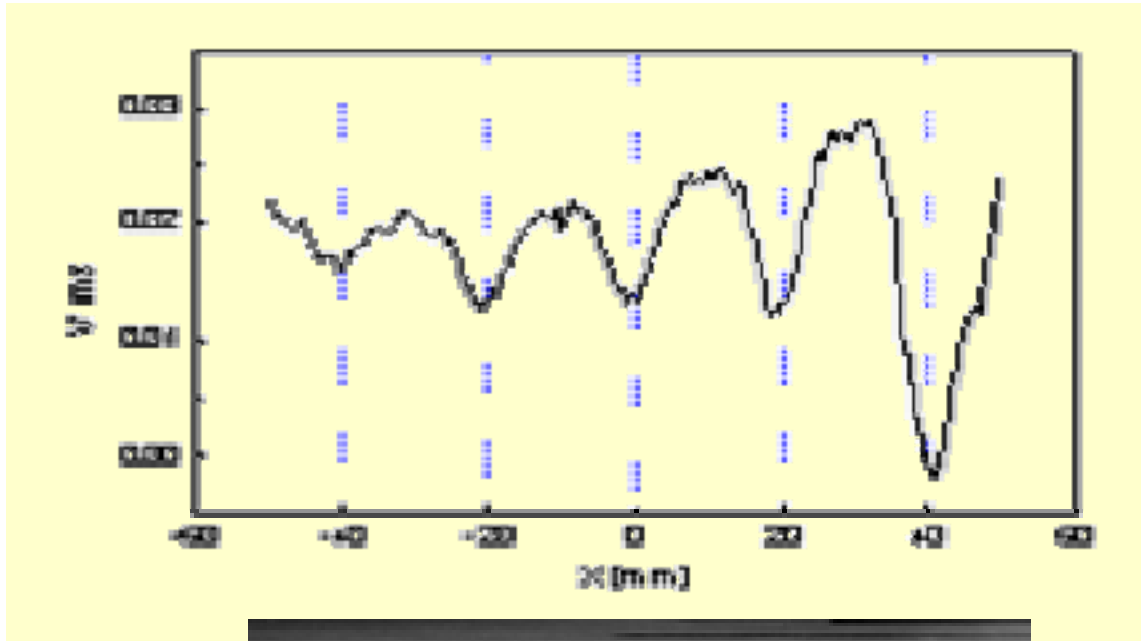


Extreme low-energy ion gun for artifact-free surface layer removal

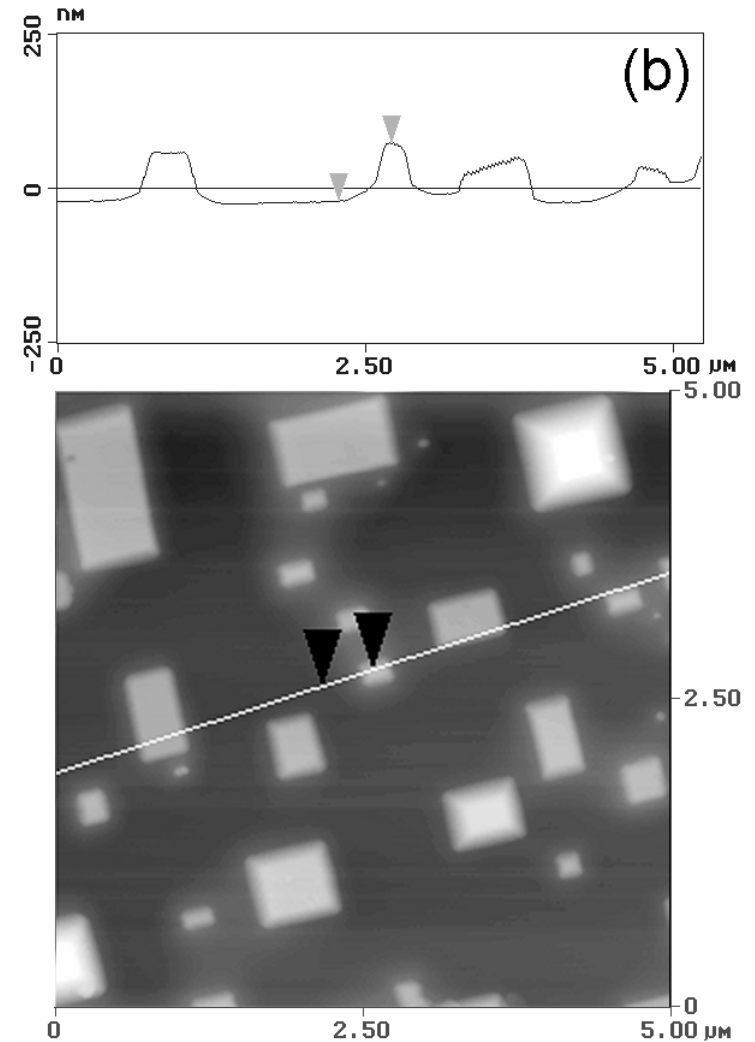
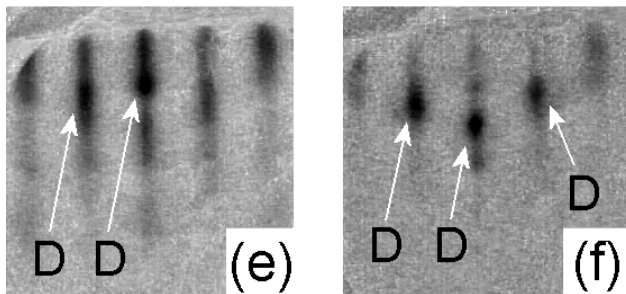
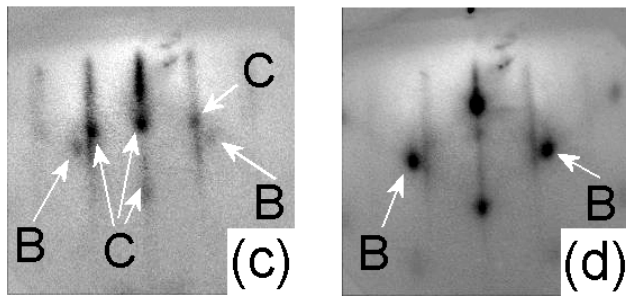
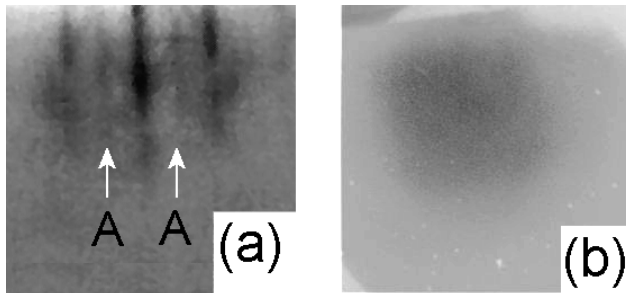
Nanotechnology, NKFP



Magnetic sensor in Eddy current measurement for metal integrity



MBE-type (UHV, RHEED) thin film deposition and nanocrystal growth

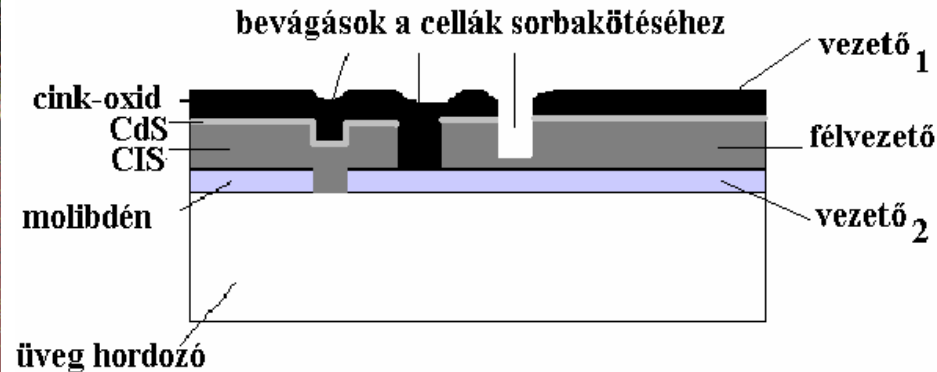


***In situ* observation of the formation of epitaxial erbium-silicide by RHEED**

AFM studies of the epitaxial ErSi island formation

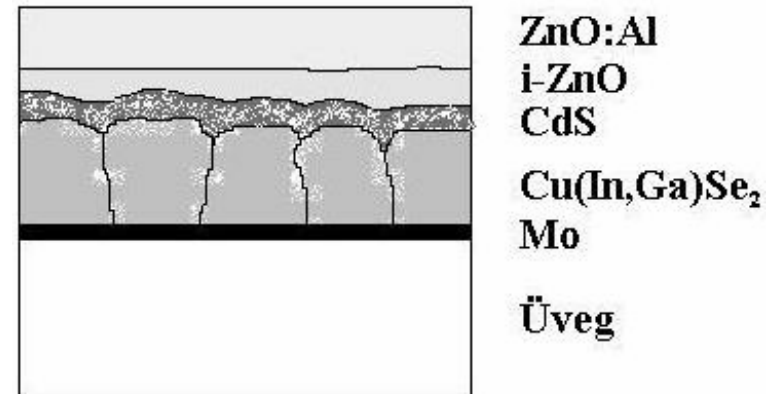
Solar cell technology

Processing line for CIGS on 30 X 30 cm² glass substrate



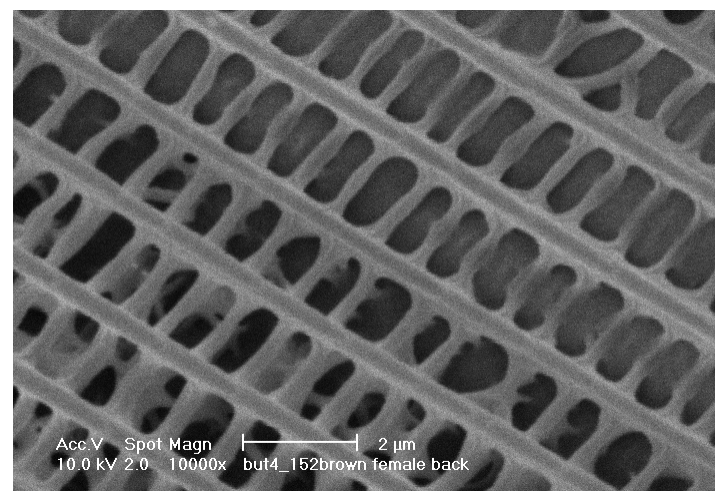
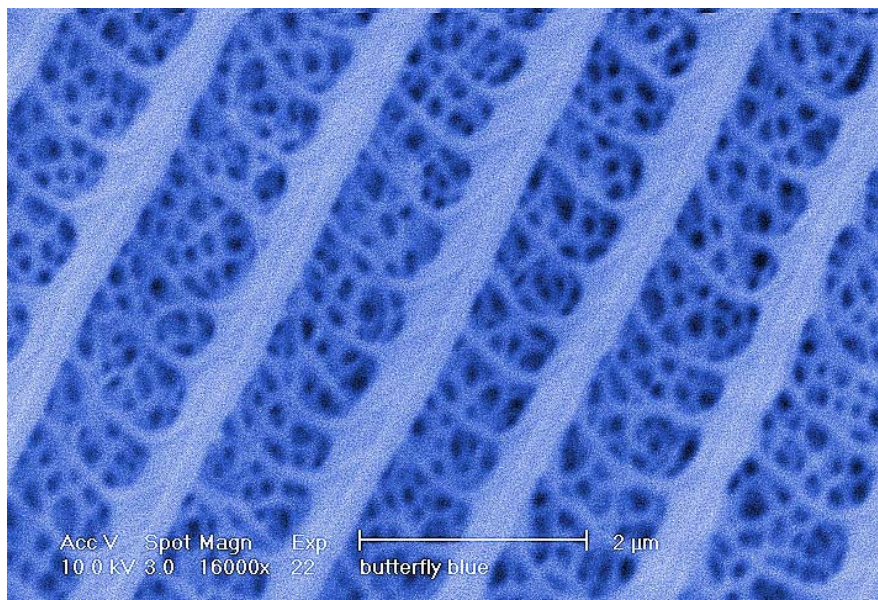
The 3-magnetron sputter unit
(Mo, ZnO)

Cross section of the device, and the
polycrystalline multilayer structure
(right)



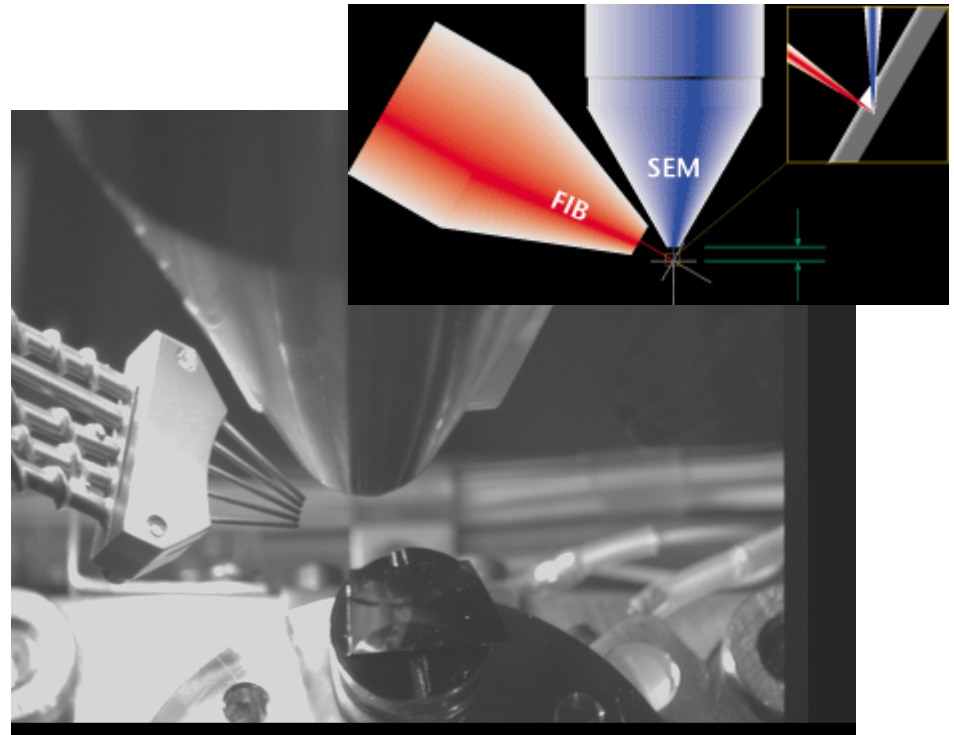
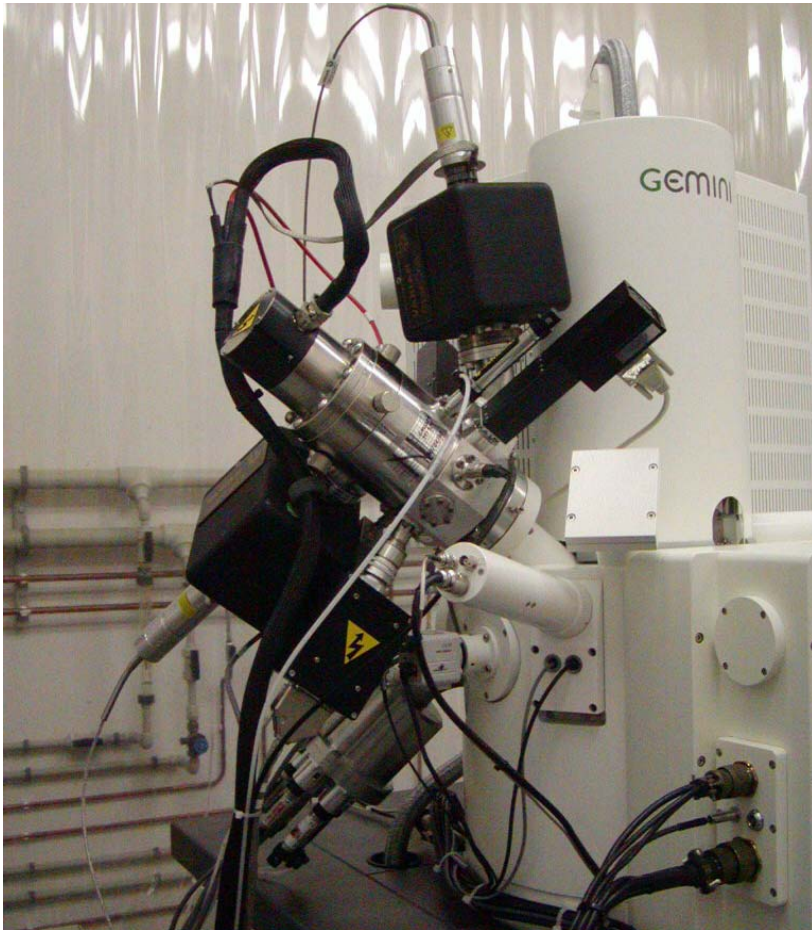


PHOTONICS is the technology of generating and harnessing light and other forms of radiant energy, whose quantum unit is *the photon*.



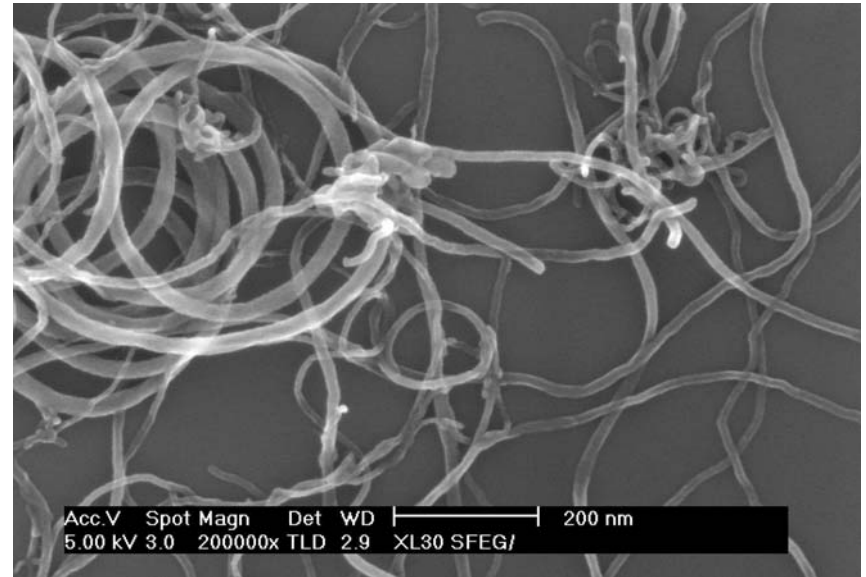
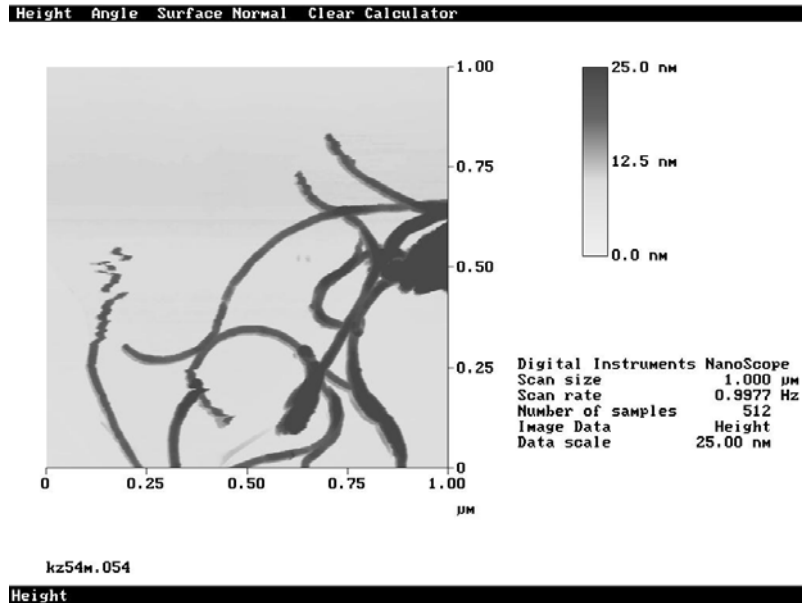
Nanostructuring facility – FESEM/FIB-GIS

LEO1540XB



LEO crossbeam system with five gaslines for etching and IBAD formation of insulators, conductors

Carbon NanoTube studies



Carbon NanoTubes imaged by AFM and FESEM using similar magnification in both techniques